# Nanostructures – density of states



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# Semiconductor heterostructures



Investigation of high antimony-content gallium arsenic nitride-gallium arsenic antimonide heterostructures for long wavelength application

# Bandgap enginee







Fig. 1. Band offsets and the Fermi level stabilization energy  $(E_{\rm FS})$  in III–V compounds. The energy is measured relative to the vacuum level. The filled circles represent stabilized Fermi energies in heavily damaged materials, exposed to high energy radiation. The open circles correspond to the location of the Fermi energy on pinned semiconductor surfaces and at metal/ semiconductor interfaces. The dashed lines show the location of the Fermi energy for a maximum equilibrium n- and p-type doping in GaAs and InP.



Suppose, that  $\phi_2 - \phi_1 \approx 1 \ eV$ Estimate the number of electrons that pass from one metal to another to create equilibrium potential difference. Assume that the distance between the metals is  $5 \times 10^{-10} m$ .

Electric field:  $E = \frac{\Delta \phi}{d} = 2 \times 10^9 \frac{V}{m}$ The surface charge:  $\sigma = \varepsilon_0 E$ The concentration:  $n^{2D} = \frac{\sigma}{e} = 1.12 \times 10^{13} cm^{-2}$ The concnetration in metal  $n^{3D} = 5 \times 10^{22} cm^{-3}$   $n^{2D} = 1.5 \times 10^{15} cm^{-2}$ Within the width of 1 lattice parameter ~1% of charge

> Electrical properties of materials Solymar, Walsh (6.11) Pg. 143

# The doping of semiconductors

Thus the electric field in the range  $(x_p, 0)$ :  $\vec{E}_A = -\frac{dU}{dx} = \frac{1}{\epsilon} eN_A(x+C) = \frac{1}{\epsilon} eN_A(x-x_p)$ Similarly for  $(0, x_n)$ :  $\vec{E}_D = -\frac{dU}{dx} = \frac{1}{\epsilon} eN_D(x+C) = \frac{1}{\epsilon} eN_D(x-x_n)$  $U = -\int_{x_n}^0 E_A dx \qquad x < 0$  $U = -\int_{0}^{x_n} E_D dx \quad x > 0$ 



$$U_{0} = U(x_{n}) - U(x_{p}) = \frac{e}{2\varepsilon} (N_{A}x_{P}^{2} + N_{D}x_{n}^{2})$$





# The doping of semiconductors

Charge conservation  $eN_A x_p = eN_D x_n = Q$ 

The total width of the depletion region w

$$w = x_n - x_p = \sqrt{\frac{2\varepsilon U_0}{e(N_A + N_D)}} \left( \sqrt{\frac{N_A}{N_D}} + \sqrt{\frac{N_D}{N_A}} \right)$$

If, say,  $N_A \gg N_D$  (*p*-type doping) then:

$$w = \sqrt{\frac{2\varepsilon U_0}{eN_D}} \quad \text{i} \quad |x_n| > |x_p|$$

if the *p*-region is more highly doped, practically all of the potential drop is in the *n*-region. The less donors are the wider this region is. (for  $N_A \ll N_D$  is vice-versa!)  $U_0 = \frac{e}{2\varepsilon}$ 

To are the  $U_0 = \frac{e}{2\varepsilon} (N_A x_P^2 + N_D x_n^2) - U_{--}$ 

**Depletion regions** 

E.g.  $N_D = 10^{15}$  cm<sup>-3</sup> for typical  $U_0 = 0.3$  V We have  $w \approx 180$  nm. If the change from acceptor impurities to donor impurities is gradual, then  $w \approx 1 \,\mu$ m



Net charge densities

p

 $x_p$ 

N⊿

 $x_p$ 

 $x_p$ 

n

Ē

+

 $N_D$ 

 $x_n$ 

 $x_n$ 

 $x_n$ 

 $\vec{E}_{max}$ 

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The metal-semiconductor junction (  $\phi_M > \phi_S$  )

Shottky barrier



Fig. 1.2. Band diagram of a Schottky diode under (a) equilibrium conditions, (b) forward bias, and (c) strong forward bias. Under strong forward bias, minority carrier injection occurs making possible near-bandgap light emission.

Light-Emitting Diodes (Cambridge Univ. Press) www.LightEmittingDiodes.org

#### The metal-semiconductor junction ( $\phi_M > \phi_S$ )



The metal-semiconductor junction (  $\phi_M > \phi_S$  )



Electrical properties of materials Solymar, Walsh

The surface of the semiconductor is usually charged



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The metal-semiconductor junction (  $\phi_{--} > \phi_{-}$  )

n-type

Schottky–Mott rule: As the materials are brought together, the bands in the silicon bend such that the silicon's work function  $\Phi$  matches the silver's. The bands retain their bending upon contact. This model predicts silver to have a very low Schottky barrier to *n*-doped silicon, making an excellent ohmic contact.

Picture showing **Fermi level pinning** effect from metal-induced gap states: The bands in the silicon already start out bent due to surface states. They are bent again just before contact (to match work functions). Upon contact however, the band bending changes completely, in a way that depends on the chemistry of the Ag-Si bonding.<sup>[4]</sup>



https://en.wikipedia.org/wiki/Metal%E2%80%93semiconductor\_junction

# WKB approximation

 $V(x) = V_b \left[ 1 - \left(\frac{x}{d}\right)^2 \right]$ 



**FIGURE 7.7.** Schottky barrier in the conduction band  $E_c(x)$  between a metal and n-GaAs. The potential is parabolic with height  $V_b$  and thickness d.



# Heterojunction



# Heterojunction



Figure 9.3: The energy diagram for the transition region of a p-n junction.



(b)



forward bias napięcie przewodzenia





reverse bias napięcie zaporowe



#### Heterozłącze (heterojunction)







We add  $\overline{E}_c^A i \overline{E}_v^A$ 



Assume that there is a positive voltage  $E_F^A - E_F^B = ev$ 



 $\overline{E}_{v}^{A_{i}}$ 

Align the Fermi levels (or the difference between them is set to applied volatge ev)



Join  $\overline{E}_c^A$  with  $E_c^B$  and  $\overline{E}_v^A$  with  $E_v^B$  with parallel curves (usually the point of inflexion is at the junction)



Restore  $\overline{E}_c^A$  on side  $E_c^A$  and  $\overline{E}_v^A$  on side  $E_v^A$ , including discontinuities at the junction.

# Triangular well

WKB approximation (Wentzel – Krammers – Brillouin) – for slowly changing potential



http://www.phys.unsw.edu.au/QED/research/2D\_scattering.htm

$$E_n = \left[\frac{3}{2}\pi\left(n - \frac{1}{4}\right)\right]^{2/3} \left[\frac{(eF\hbar)^2}{2m}\right]^{1/3}$$

#### The metal-semiconductor junction ( $\phi_M > \phi_S$ )



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